

ABSTRACT**MATCHING NETWORK DEVICE AND SYSTEM THEREOF**

5 A matching network device, coupled between an RF generator and a plasma
processing device, comprises an impedance matching module, a control module and a
detection module. The control module is coupled to the impedance matching module and
has a default mode. The default mode according to the impedance range of the plasma
processing device indicates matching impedance conversion of the impedance matching
10 module. The detection module is coupled among the control module, the RF generator
and the plasma processing device. When the detection module detects the impedance of
the RF generator and the plasma processing device to output a detection signal to the
control module, the control module adjusts the default mode according to the detection
signal, so that the impedance matching module transmits an RF energy outputted by the
15 RF generator to the plasma processing device.

[FIG. 1]